

This is a high NA infinity corrected objective lens for laser processing (femtosecond laser). Its glass-thickness- compensation optical design makes it possible to realize an ideal beam spot size and quality even if it was processed thorough a cover glass.

- They are designed to correct aberration depending on the thickness of cover glass. (t=0.7mm)
- With its long working infinity correction function; this objective lens can be used for a laser system and coaxial observation.
- It is also used for the observation of Near Infrared light.
- This objective lens can be used with a pulse laser of visible light (532nm).
- Laser Damage Threshold(reference): 0.1/cm² (532nm), 0.15 J/cm² (780nm)

(Laser pulse width: 10ns, repetition frequency: 20Hz)



- Available fixed objective lens holder (LHO-26).
 - WEB Reference Catalog Code W4024
- ▶ When the objective lens is fixed to a 2 axis holder, please consult our Sales Division.
- ▶ For laser processing, we offer a dichoric block (DIMC) and for laser unit with coaxial illumination and observation (OUCI-2).

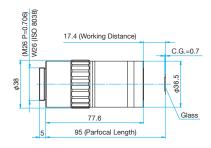
ce Catalog Code W2041, WEB Reference Catalog Code W2012

Attention

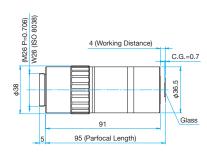
- ▶ When an objective lens is used in laser processing, use the diameter of the incident beam to extend to a size of half the pupil diameter $(1/e^2)$. A small light spot cannot be achieved when the incident beam is too narrow. Please note if there is a laser energy density increase, there will be a high possibility of damage to the objective lens.
- ▶ When the thickness of cover glass is not same as the specified, designed specifications may not be achieved due to aberration.
- If the incident laser beam femtosecond is below 100fs, there is a possibility that the pulse width will spread.
- ▶ Magnification is the value when using the imaging lens f=200mm. When used in a microscope lens barrel from other manufacturers there may be different magnifications. The actual magnification should be calculated from the ratio of the focal length of the objective lens and the focal length of the imaging lens to verify the focal length of the imaging lens barrel to be used.

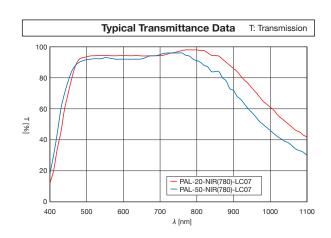
Outline Drawing

PAL-20-NIR(780)-LC07



PAL-20-NIR(780)-LC07





Specifications										
Part Number	Item name	Magnification		Numerical aperture NA		Resolution (λ=550nm) [μm]			eld of view (Imaging device 1/2-inch) [mm]	Weight [kg]
PAL-20-NIR(780)-LC07	LCD PlanApo NIR(780) 20x (t0.7)	20×	10	0.45	17.2	0.6	±1.4	φ1.2	0.24×0.32	0.34
PAL-50-NIR(780)-LC07	LCD PlanApo NIR(780) 50x (t0.7)	50×	4	0.80	3.8	0.3	±0.4	φ0.46	0.10×0.13	0.44

Application Systems

Optics & Optical Coatings

Opto-Mechanics

Bases

Manual Stages

Actuators & Adjusters

Motoeized Stages

Light Sources & Laser Safety

Index

Microscope Unit

Alignment

Interferometers Inspection/ Observation

Bio-photonics

Laser Processing